

# WAFER HOLDER FOR SEMICONDUCTOR MANUFACTURING DEVICE AND SEMI-CONDUCTOR MANUFACTURING DEVICE IN WHICH THE HOLDER IS INSTALLED

## Abstract

Affords for semiconductor manufacturing devices a wafer holder and a semiconductor manufacturing device in which it is installed, where in the wafer holder, which has a wafer-carrying side, the isothermal quality of its wafer-carrying side is enhanced. A shaft that supports the wafer holder having a wafer-carrying side is joined to the wafer holder, wherein by making a distance  $a$  between the center axis of the shaft and the axial center of the wafer-carrying side 5% or less of the diameter  $L$  of the wafer-carrying side, the temperature distribution in the surface of a wafer set into place on the holder can be brought to within  $\pm 1.0\%$ . Moreover, making the distance  $a$  1% or less of the diameter  $L$  enables the temperature distribution to be brought to within  $\pm 0.5\%$ .